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ARTICLE INFO

ABSTRACT

Keywords: С ٠, • (3DG) . • w ·___ ٦ Т **۲** Η -' w ٩. ff С ۱ (SLM) (3D) - 14 1 s • (CVD) . G • w 🔪 in-situ w٩ С С • 🔺 🤄 3DG . A • w CVD w E SLM ff ۰. 3DG () <u>.</u>)) ff . T 3DG/ ff 88% 27% `• • Ċ 5 (EMI) . P ffi-5 ff EMI 5 (SE) ٦ 47.8 B 2.7 GH SE 32.3 B 2–18 GH . Т · -SLM

1. Introduction

G sp w . wi (2630 ****² $^{-1}$) 10^5 \mathbf{v}^2 V^{-1} (2 ⁻¹) $(5000 \text{ W} \ \text{--}^{-1} \text{ K}^{-1}) 2 . \text{ H}$ w π-π (2D) w ٠. , w 3.A w . . C 1 • (3DG) 99.7%), w (w fi . (0.6 fi w ١. w

(2DG), 6,7, (EMI) 3DG ٦ 9 10 •. H w F ff 13 15 Μ CVD < 16 . B w

*C : G : , W : 430074, PR C : . E-mail address: : @ . . . (. L).

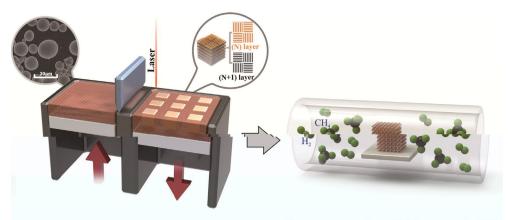
:// _ /10.1016/. R _ 31 J _ 2020; R _ 2 _ 1 A _2020; A 13 A _2020 Available online 18 April 2020 1359-835X/ © 2020 Elsevier Ltd. All rights reserved.

fi ʻıfl), 5 • (:_., 3DG. B) ٩. 3DG w -(:_., _). H w ffi ۹ Ν. ٦ ٩ • 3DG ۰, w -17,18. fi Η、 ٦ w 3DG w 🖢 19 S (SLM), ٦ (AM) (3D) ٠. ffi . . w fl in-situ 🤊 ٦ Т ٩ SLM Т 20 21 , 🔹 N 🖕 Ľ 22.C w 1 Ν. С w CVD (< 0.001 %) w w • • w ۰. 23.W 📜 Nʻ w %) (> 0.1 ۰ fi ۹ 17 24.H w SLM ż ffi 5 ٦ w ٦ fl • ٦ w w ٦ (1000–1100 **••**). F ff ٦ SLM ٠, 25. ٦ Т fi 3 , w (3DG/C) 3DG/ __ SLM · · w · CVD w İ٩, ۰. A w w __ SLM <u>نا</u> ۲ 1 ۹

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Copper substrate fabricated via SLM Graphene growth on SLM copper via CVD

ff ff Fig. 1. I ٠. 3DG/C : _ SLM () 🔪 in-situ ∵.fi _____ CVD (_____). (F 5 ٠, ١. w .)

ASTMB193-2002 w 2 2 20 🗨 🗨 3 • • ff . T ٠, . (2 10 •••³) • 10 ٦ ٩ 10 • •³) w ASTME1461-2013 w (5 10 **N**IN W 1. 1. ŗ LFA (L fl -LFA457, G 🧨 🔹). R 🗨 🕻 (SENTERRA, B Ν , 3DG/C ff G **v** () w w . • 514 **.** T S • (S11 、 S21) w w (VNA, A 🐪 • PNA-N5244A, -٦ • w w SE , SE US) 2-18 GH . T . w SE fl ı ا E. 2–5 🖪 S I٦ -١. 1

3. Results and discussion

3.1. Formation of SLM copper

3.1.1. SLM manufacturing of copper under different line energy densities T T ff (w) () w) D ff)

'ı w 'ı w (F <u>_ 2)</u> ٦ 'n ٦ 3 , i 30% w • (A), 26.7% 3 'n • (B), 16.7% (C) 126.7% 1 1 'n ٦ 'n • (D). D ff ۰, LED (J/~) 27 (E.6, <mark>SI</mark>). T ٠, fl . Т ffi w ffi A, 113 w Ľ ffi w B. w w w fi ffi w 1 1 1 LED 400 J/ 🗨 (• C). W LED 130 µ**ч** w (> 800 J/ ◄) • D), w 📜 ٦ (w w 113 28. w w

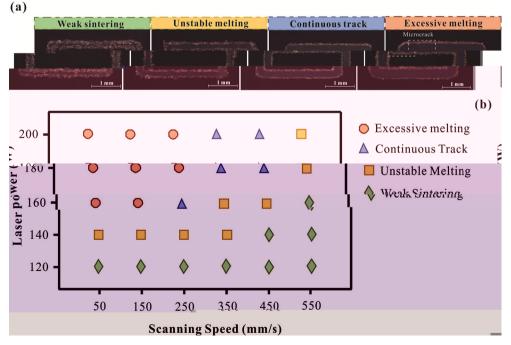


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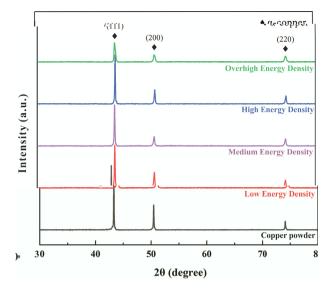
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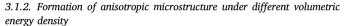
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Т 🤊 🤄 α-1 XRD (111) (200) fl ff $2\theta = 43.32$. . w ·____ (F ·__ 3), · $2\theta = 50.45$, (1 1 1) ٦ XRD Τ. Γ. • -٠, ٦. 3 j. ff 'n. 5 w ٩. ٩ ۱ ٦ 1 fiv • • w SLM ff ٠, SLM . IN ff . 29 т w SLM 5 . T w w

:() <u>i</u> -w , (``) 3000 J/ ◄ ◄³ (F :.. 4a), . A w. 180 μ**¬**, w . w . ۲ 1/7 • (F 📜 4**d**). T Μ . 30 _ fl ۱ ۱ ٦ • ٩. ٦ . Т w 5 'n ۱ fi w 5 . W . 3 857 J/ w w ٦ w 4 ._. **4b**). (F 1 U٩ ۱ fi-96.2% w , wʻ_ . H w 'n. Т K^{-1}), (398 W i ffi 📜 (F : 4c). G w М -В ٤ ŗ, SLM 31 . I **1** 128 J/ • •³. w 347 w ww fi ۱ ۱ 88.6% (F . 4d).

٠, SLM т 'n. w w٩ (F 🛄 5). T . • w w w **.** T wi w w , w w 32. T fi fl w Ľ . S 🛪 . W. . 33, w **1** <u>1</u> 1 Ľ



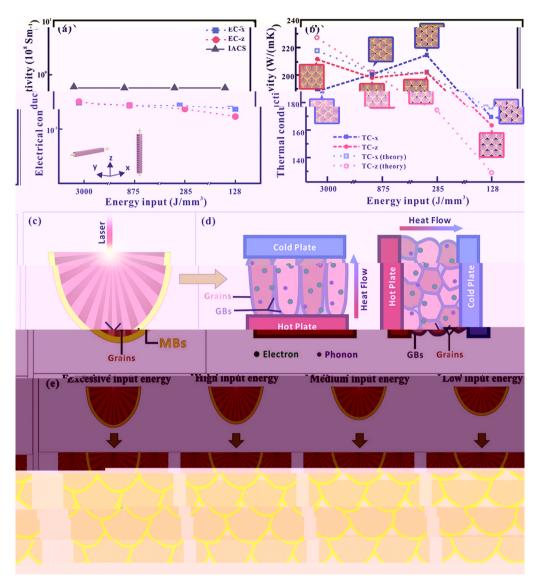


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3.3. Morphology and structure of CVD 3DG/Cu porous scaffolds

F٦ w :_ $\mathbf{f}\mathbf{f}$ ff w 1 ff . G w 🔪 in-situ CVD ۹ А 'n w ٦ ff fi 🤊 39 . A 5 w w w 33 🥆 V (25 39.U 1 ۹) ٤. N;L: С 40 ٦ w Ηw (. 23 41) w CVDw٩ fl Ŀ . 1 Ŀ w ٩ w

. A , w 3 SEM, w SEM Т 3DG/C ff <u>ن</u> ۱ w :_ w 450 μ 🛰 (F 📜 8a). Α ١. ٩fi (F 📜 8b), ۱fl w ff т ۹ ۱ff EDS , '_ヽ (F '_. 8c-d), w • ۰fi ۲ Ľ **`_ •.** A ١fi ۰ fl w (F . 8e-g). T 3DG/C ff Ľ w (F 📜 8h). w R 3DG/C ٦ w • 'n 5 • Т G-(~ ٩. ¹) ¹) 1590 2D-(2699 w ٩ w · · ٩ 42 (F 8). S 🤄 ۹ w ¹) fl D-• (~1350 j 1 • 43, 5 D G $(I_D/I_G) w$ ٩ ٠.

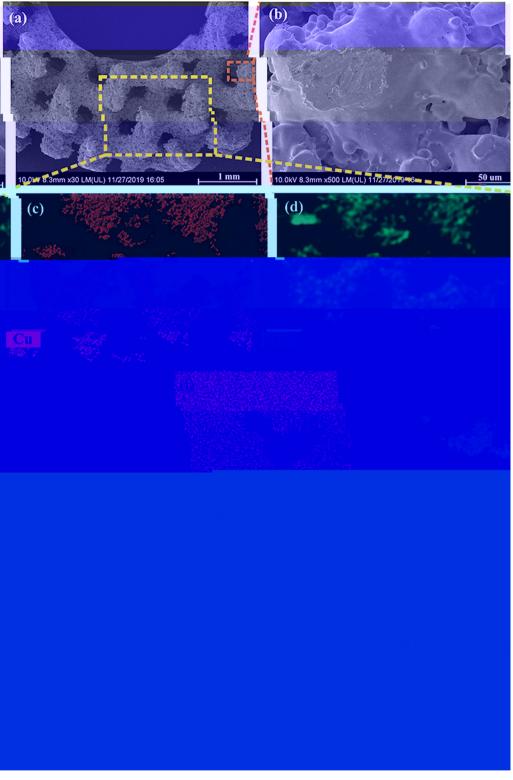


Fig. 8. (-) SEM 🖱 3DG/C ff ff ۹ ۱fi 🔄 ; EDS 🤊 ()C ()C;() ۲. ti ... SEM 🔄 ٩. ٠. ٠. , 2 2 () C () C; () * 🔹 EDS 🤜 <u>ن</u> ، OM; ().R 🧨 🐧 $\mathbf{f}\mathbf{f}$ w ff v w ∵_fi . ٦ ·_ .) • ٩, . w

fl w . W . w 0.93, i ◄ 0.71 -ي ۱ I_D/I_G i 1 I А ٦ 3 w (w , 1000 C, fl w CH₄ 3 30 ٦ w 3 20 🛰 🖢) w 3DG/C

3.4. Thermal property and EMI shielding effectiveness of 3DG/Cu porous scaffolds

Т 🗨	ff 📜	٩.٩	۰.	1	٩
		С	ff,	26.8%	· ·
۹.	3		N . N	14.8%	<u>.</u>

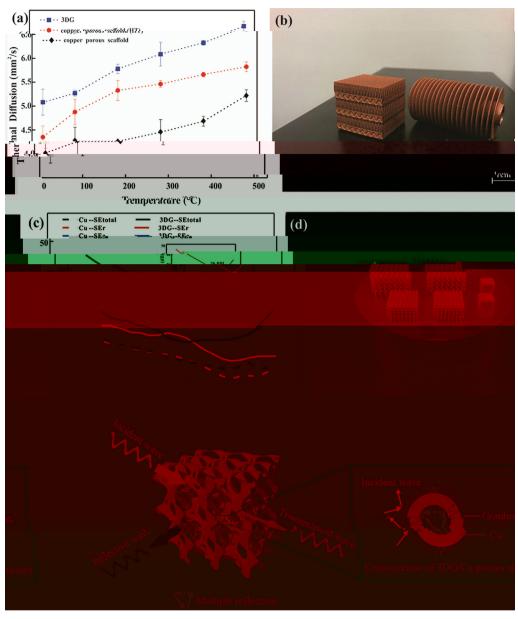


 Fig. 9. P
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Table 1

Coating materials	Substrate	Method	Maximum shielding efficiency (dB)	Improvement of thermal property (%)	Ref
G .	G	Inn _1++, +	37	-	50
G	PS	H+	29.3	_	56
G	PMMA	S <u>1 1 1 + 1 1 1 1 +</u>	19	-	57
C/G /C	А	S • fi • + • •	_	8.5	58
G	N .	$F \rightarrow CVD$	-	554	59
G	C-N	E 1 +	20	_	60
G	С	P w + CVD	-	2.4	61
G I	С	F - 1 + • • 1	47	6.3	62
G	С	CVD + SLM	47.8	27	T

Note: (• •)-PPMA, • -PS.

HT in-situ w (F. 9a). S 1 3DG/C ff I w 1 HT W 1-2 W W

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(w - 3 + fl - 500 μ *)
(F - 9b),
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(F - 9b),
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N - N

3DG/C т • ff EMI, EMI SE, w 📜 ۰. • (EM) . , w 2–18 GH (**F** ⊆ 9**c**), , W in-situ W٩ • ◄ 15.9 ff 32.3 B, w 47.8 B (88.2%), 20 B.T 3DG/C ∖fi ◄ 'n w . J .K w _ 1 44 EMI _. т <u>.</u> EMI SE • **133%** • • w . • i) **◄** 20 110 PPI (<u>ن</u>). (: R Κ 45 i. wʻ EMI • • . W ٦ . . j. ٩. 1 5 ▼ 17 26 PPI (F :.. 9c insert) 105% 、 • • EMI SE. I w EMI • ff SLM. T w 3DG/C • 26 PPI ۹. EMI SE 32.3 B, EMI w .T 5 99.9% i 60 🤜 i ٦ ۷ N ff) 46 . T EMI **•** (30 ٦ Ľ 3DG/C w ٩- ١ × . **1**. I EMI SE ЪT 3DG/C 'n w ۹.Ξ 3D 5 •

(SE_r), Т ۰. EMI fl 47, fl _ (EM) w (SE_a) w • 48.R fl w . W Т EM w w • EMI 50 . R 3 W fi С 51.F ۹٩, 'n w 52 S O₂ 53.W 5 3DG/C ff ۰. w 1 1

lifi i w . w \ `. F `.. 9e. W \ SE_r \bullet SE_a, w <u>ن</u> ا 3DG/C w ff fl w 347 347 <u>،</u> . ff ٦ i i w S 3DG/C fl **•** • w wi S S EM w • EM w SE. 01 ٦ EM fi EM ****-Т 54 fl w EM w EM w т 347 44 т 3D 3 EM w CVD . IN R 3.3 ٦ 55 ٠. I EM w w . . 'n. 01 3DG/C fl ١fi w **٩**. T ff ۰.

4. Conclusions

3DG/C А ff W. ٩ wʻ in-situ _ CVD 🧨 w · • • ff 3DG/C SEMI SE 1 1 4 1 • 15.9 () 32.3 B, 47.8 B (88.2% i), w 26.8% i ff C. T C 3DG/C ff i fl i, fl ۲. ۲. ٦ SEMI S N 3DG/C ff L SEMI L

Credit authorship contribution statement

Declaration of Competing Interest

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Acknowledgement

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Appendix A. Supplementary data

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